

Notice of References Cited	Application/Control No. 10/667,823	Applicant(s)/Patent Under Reexamination NOZAWA ET AL.	
	Examiner Rodney G. McDonald	Art Unit 1753	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-6,428,663	08-2002	Mostovoy et al.	204/298.12
	C	US-6,162,297	12-2000	Mintz et al.	118/715
	D	US-5,824,197	10-1998	Tanaka, Yoichiro	204/192.12
	E	US-5,248,402	09-1993	Ballentine et al.	204/298.2
	F	US-4,933,063	06-1990	Katsura et al.	204/298.03
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	I	US-			
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	K	US-			
	L	US-			
	M	US-			

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	N	01-173718	07-1989	Japan	Fujikawa et al.	
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kim et al. "Attenuated phase-shifting masks of chromium aluminum oxide", Applied Optics, Vol. 37, No. 19, pp.4254-4259, July 1, 1998.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.